

MAY 16 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Jeffrey W. Carr  
Appln. No.: 10/608,384  
Confirm. No.: 7970  
Filed: June 27, 2003  
Title: Apparatus and Method for Reactive Atom  
Plasma Processing for Material Deposition


PATENT APPLICATION

Art Unit: 1765  
Examiner: Vinh, Lan  
Docket No. CARR-1000US4

Customer No. 23910

CERTIFICATE OF TRANSMISSION/MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

 (Signature)  
Patricia A. Diehl  
Signature Date: 5-16-06

REPLY TO OFFICE ACTION UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This Reply is in response to the Office Action dated December 15, 2005.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.

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